



ISC Audits & Reviews SC Summary May 2016

Doc. #	Title	Result
5274G	Revision to Add a New Subordinate Standard: Specification For Sensor/Actuator Network Specific Device Model Of A Generic Equipment Networked Sensor (GENSen) To SEMI E54-0413, Sensor/Actuator Network Standard	Passed
5818	Line Items Revision to SEMI HB1-0315, Specifications for Sapphire Wafers	
LI1;	Correct the title of this standard from “Specifications” to “Specification”;	Passed
LI2;	Modify and update Table 1, 2-3,3 Flat length;	Passed
LI3;	Implement r-plan direction in Table 1, Table 2 and Table R1-1, Part 2;	Passed
5819A	Reapproval of SEMI E114-0302E (Reapproved 0309) Test Method for RF Cable Assemblies Used in Semiconductor Processing Equipment RF Power Delivery Systems;	Passed
5820A	Reapproval of SEMI E115-0302E (Reapproved 0309) Test Method for Determining the Load Impedance and Efficiency of Matching Networks Used in Semiconductor Processing Equipment RF Power Delivery Systems;	Passed
5829B	Line Item Revision to SEMI E171-0515 Specification for Predictive Carrier Logistics (PCL)	
LI1;	Rename old mnemonics left nonreplaced in Figure 9, Figure 10, Figure A1-1, Figure A1-4, Figure A1-7, Figure A2-3, and Figure A2-4 to new ones;	Passed
LI2;	Rename old mnemonics left nonreplaced in Figure A1-3, Figure A1-6, and Figure A1-9 to new ones, and add columns for CLJ attributes ‘URPState’ and/or ‘LSPState’ as needed to make the table more understandable;	Passed
5894	Line Item Revision to SEMI PV10 Test Method for Instrumental Neutron Activation Analysis (INAA) of Silicon	
LI1;	Change 4 N to 3 N in 10.2;	Passed
LI2;	Add section 4.4, note 9 after note 8, and note 10 after A1-2.6.;	Passed
5913	Reapproval for SEMI E157-0611 Specification for Module Process Tracking;	Passed
5914	Reapproval for SEMI E54.3-0698 (Reapproved 1110) Specification for Sensor/Actuator Network Specific Device Model for Mass Flow Device;	Passed
5927	Revision of SEMI PV22-1011 Specification for Silicon Wafers for Use in Photovoltaic Solar Cells ;	Passed
5944	Revision to SEMI F63-0213 Guide for Ultrapure Water Used in Semiconductor Processing;	Failed
5950	Reapproval of SEMI E1-1110 Specification for Open Plastic and	Passed



Doc. #	Title	Result
	Metal Wafer Carriers;	
5952	Reapproval of SEMI E117-1104 (Reapproved 0710) Specification for Reticle Load Port;	Passed
5955	Line Item Revision of SEMI E63-1104 (Reapproved 1110) Mechanical Specification for 300 mm Box Opener/Loader to Tool Standard (BOLTS-M) Interface with Title Change to: Specification for 300 mm Box Opener/Loader to Tool Standard Mechanical (BOLTS-M) Interface	
LI1;	Correct title and concomitant text of SEMI E63;	Passed
5956	Line Item Revision of SEMI E57-0600 (Reapproved 1110) Mechanical Specification for Kinematic Couplings Used to Align and Support 300 mm Wafer Carriers with Title Change to: Specification for Kinematic Couplings Used to Align and Support 300 mm Wafer Carriers	Passed
LI1;	Correct the title of SEMI E57;	Passed
5965	Reapproval of SEMI E15-0698E2 (Reapproved 0310) Specification for Tool Load Port;	Passed
5969	Line Item Revisions to SEMI S2-0715 Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (Re: Fire Protection)	
LI2;	Restructuring of portions of Section 14.;	Passed
5970	Line Item Revisions to SEMI S14-0309 Safety Guidelines for Fire Risk Assessment and Mitigation for Semiconductor Manufacturing Equipment	
LI1;	Changes to Terminology to Align with SEMI S10. ;	Failed
LI2;	Change "Grouping" to "Group" to Align with SEMI S10.;	Passed
LI3;	Changes to Risk Categories to Align with SEMI S10.;	Passed
5972	Reapproval of SEMI S19-0311 Safety Guideline for Training of Manufacturing Equipment Installation, Maintenance and Service Personnel;	Passed

Line Item (LI)

Document 5944 and Document 5970 (LI1) **failed**. All other documents passed and will be forwarded to Standards Publications for final processing.

KN
VI
May 11, 2016